

Substitute for form 1449/PTO <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  Date Submitted: April 13, 2009 (use as many sheets as necessary)		<b>Complete if Known</b>	
		Application Number Filing Date First Named Inventor Art Unit Examiner Name Attorney Docket Number	10/588,698 02/02/2005 Tadahiro OHMI et al. 2895 Caridad Everhart 039262-0156
Sheet	1	of	1

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code <sup>2</sup> (if known)			
	B1	US - 4,484,979	11-27-1984	STOCKER	
	B2	US - 5,296,094	03-22-1994	SHAN et al.	
	B3	US - 6,025,255	02-15-2000	CHEN et al.	
	B4	US - 6,159,862	12-12-2000	YAMADA et al.	

UNPUBLISHED U.S. PATENT APPLICATION DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	U.S. Patent Application Document	Filing Date of Cited Document MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Serial Number-Kind Code <sup>2</sup> (if known)			

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Documents	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>
		Country Code <sup>3</sup> Number <sup>4</sup> Kind Code <sup>5</sup> (if known)				
	B5	JP - 08-222551	08-30-1996	SONY CORPORATION		A
	B6	JP - 09-027472	01-18-1997	SONY CORPORATION		A

NON PATENT LITERATURE DOCUMENTS				
Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.		T <sup>6</sup>
	B7	GOTO et al., "A New Microwave-Excited Plasma Etching Equipment for Separating Plasma Excited Region From Etching Process Region," Japanese Journal of Applied Physics, Vol. 42, Part 1, No. 4B, April 2003, pp. 1877-1891.		
	B8	KAIHARA et al., "Damage-Free Contact Etching Using Balanced Electron Drift Magnetron Etcher," Proceedings of ISSM 2000, The 9 <sup>th</sup> International Symposium on Semiconductor Manufacturing, Vol. Conf. 9, September 26, 2000, pp. 102-105.		
	B9	MATSUI et al., "Mechanism of Highly Selective SiO <sub>2</sub> Contact Hole Etching," Plasma Sources Science and Technology, Institute of Physics Publishing, Vol. 11, No. 3A, August 1, 2002, pp. A203-A205.		

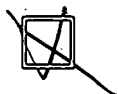
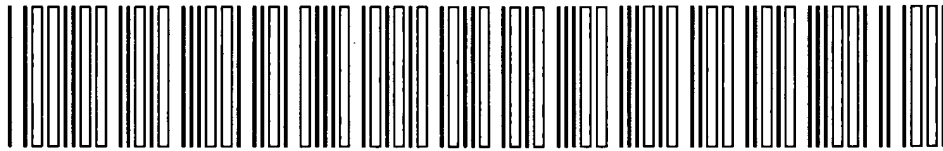
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# IDS REFERENCES



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